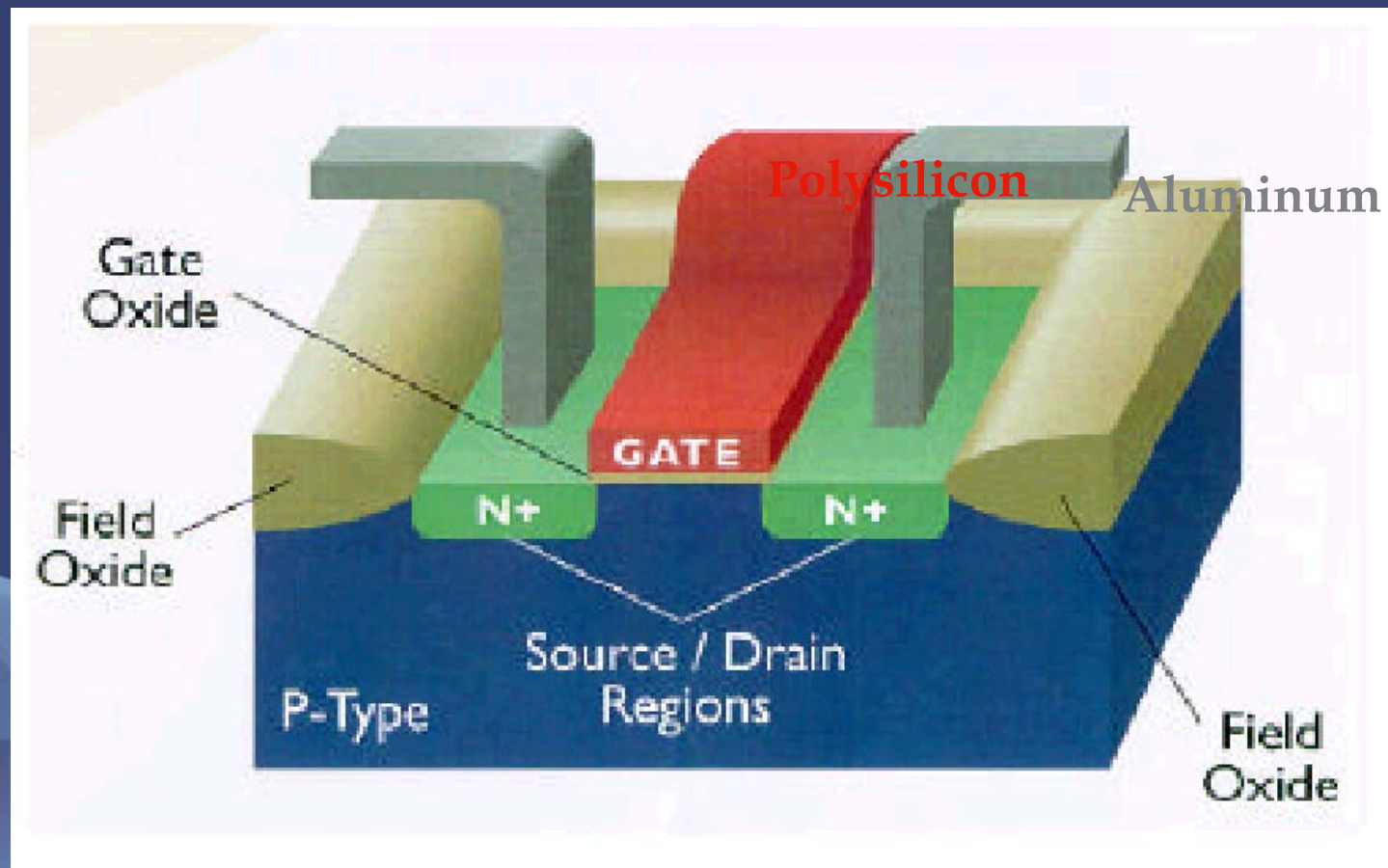


ECE 225
High-Speed Digital IC Design
Lecture 10

MOSFET Scaling

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The MOS Transistor



Review Lecture 7 and 8 from ECE 124A for basics of MOSFET Operation...

Goals of Technology Scaling

- Making things cheaper
 - Integrating more transistors per chip for the same money
 - Build same products cheaper, sell same part for less money
 - Price of fabrication of a transistor to be reduced
- But also want the transistor to be faster, smaller and low power

Technology Scaling

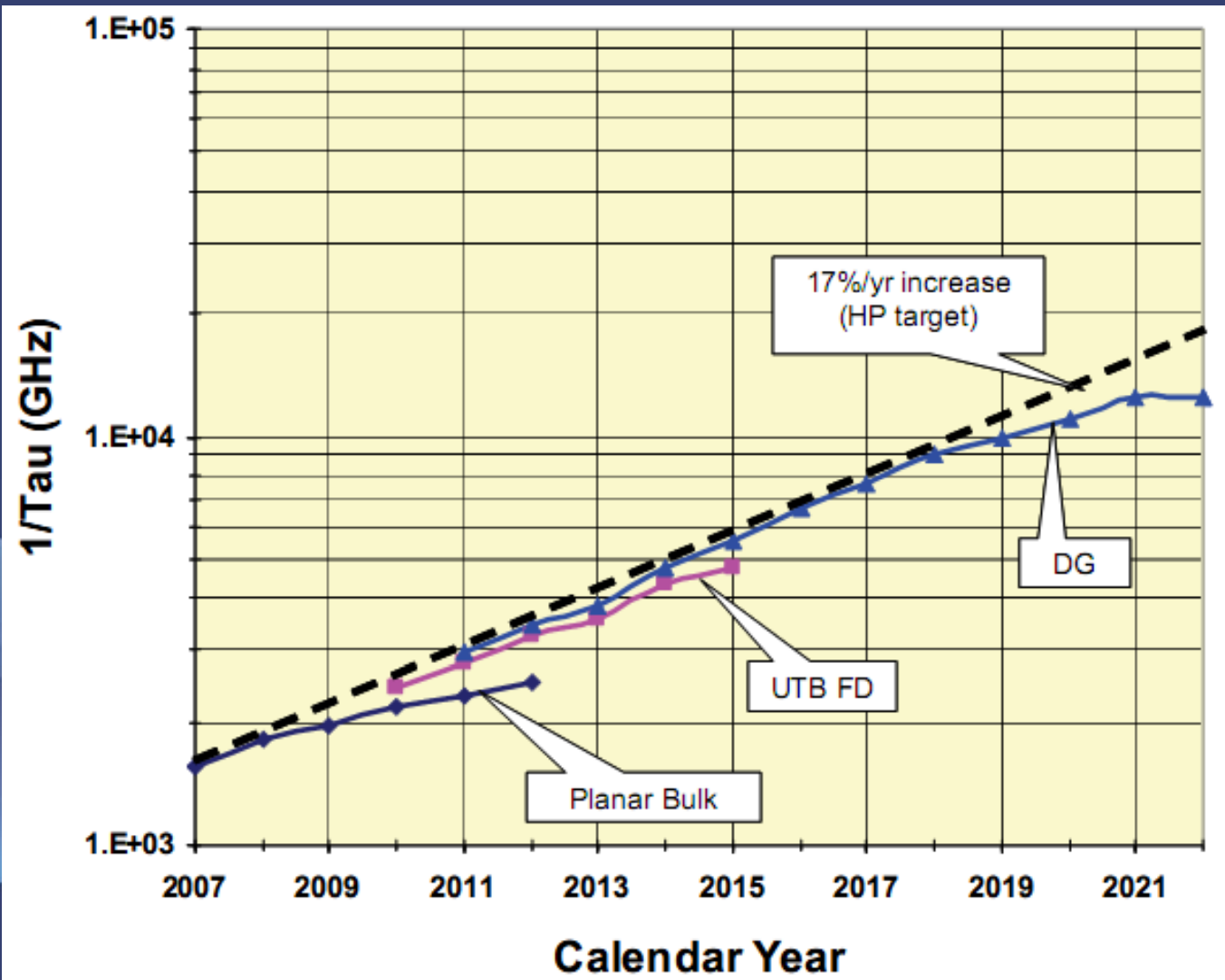
- Technology generation spans 2-3 years
- ☐ Benefits of scaling the dimensions by 30%:
 - ☐ Reduce gate delay by 30% (increase operating frequency by 43%)
 - ☐ Double transistor density
 - ☐ Reduce energy per transition by 65% (50% power savings @ 43% increase in frequency)
- ☐ Die size used to increase by 14% per generation

Technology Roadmap

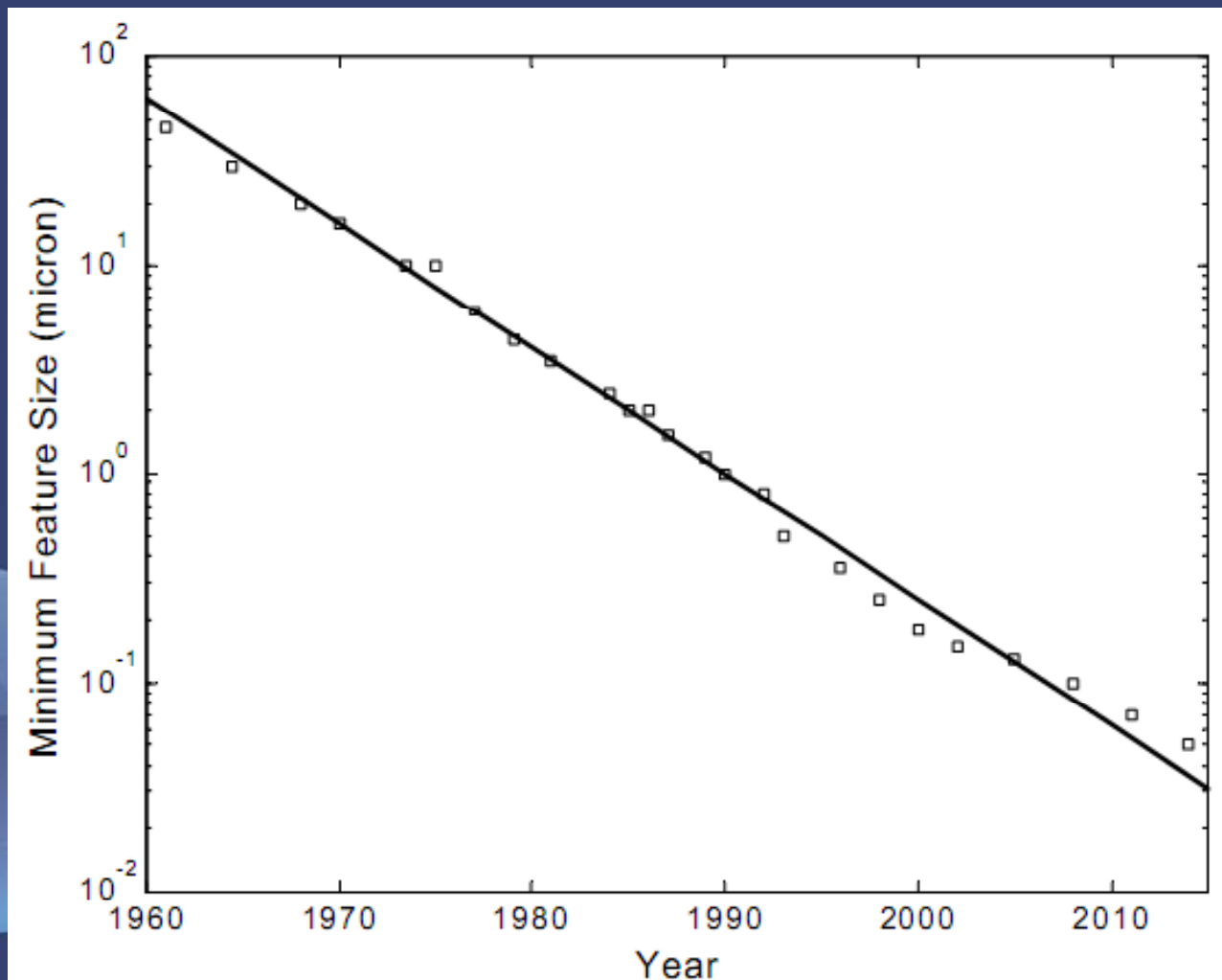
- International Technology Roadmap for Semiconductors 2002 data

Year	2001	2003	2005	2007	2010	2013	2016
DRAM ½ pitch [nm]	130	100	80	65	45	32	22
MPU transistors/chip	97M	153M	243M	386M	773M	1.55G	3.09G
Wiring levels	8	8	10	10	10	11	11
High-perf. phys. gate [nm]	65	45	32	25	18	13	9
High-perf. VDD [V]	1.2	1.0	0.9	0.7	0.6	0.5	0.4
Local clock [GHz]	1.7	3.1	5.2	6.7	11.5	19.3	28.8
High-perf. power [W]	130	150	170	190	218	251	288
Low-power phys. gate [nm]	90	65	45	32	22	16	11
Low-power VDD [V]	1.2	1.1	1.0	0.9	0.8	0.7	0.6
Low-power power [W]	2.4	2.8	3.2	3.5	3.0	3.0	3.0

Acceleration Continues

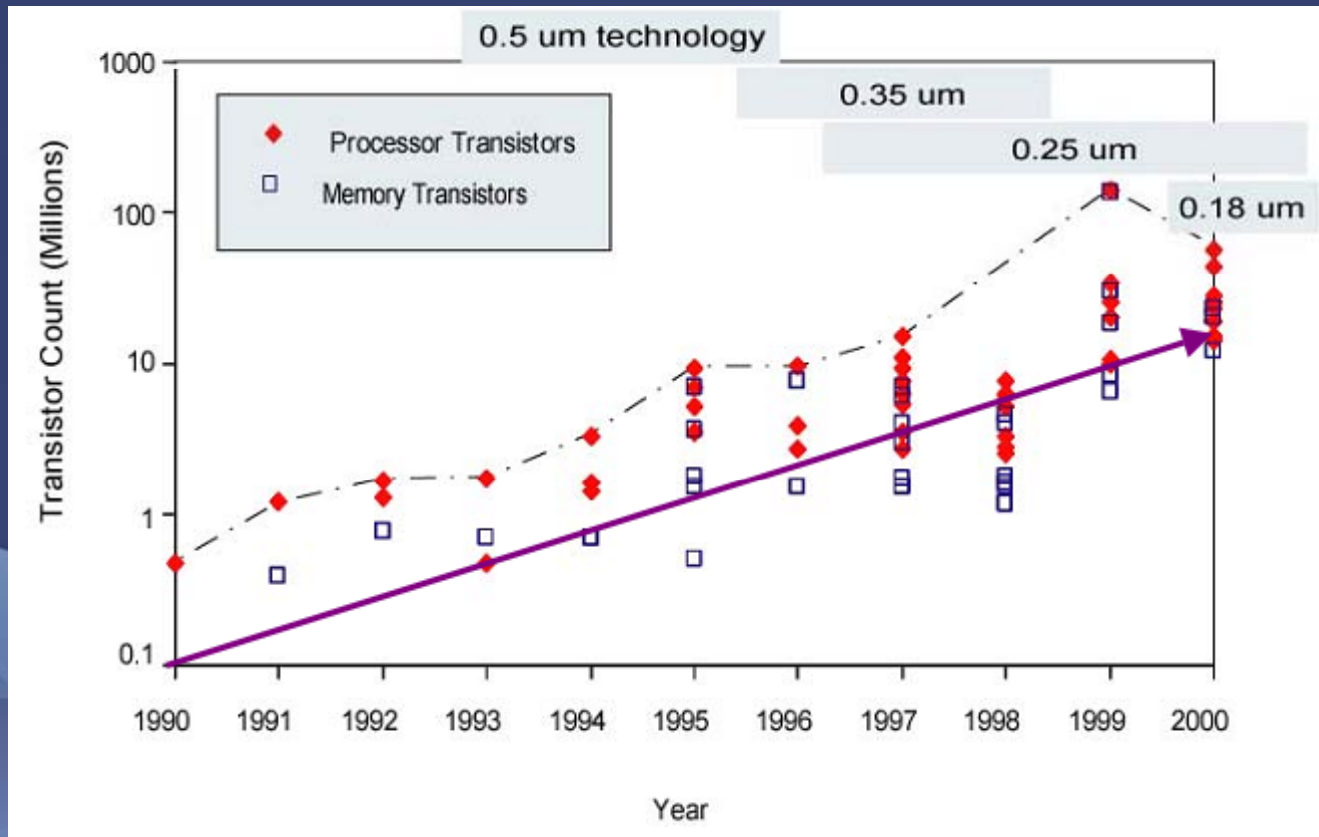


Technology Scaling



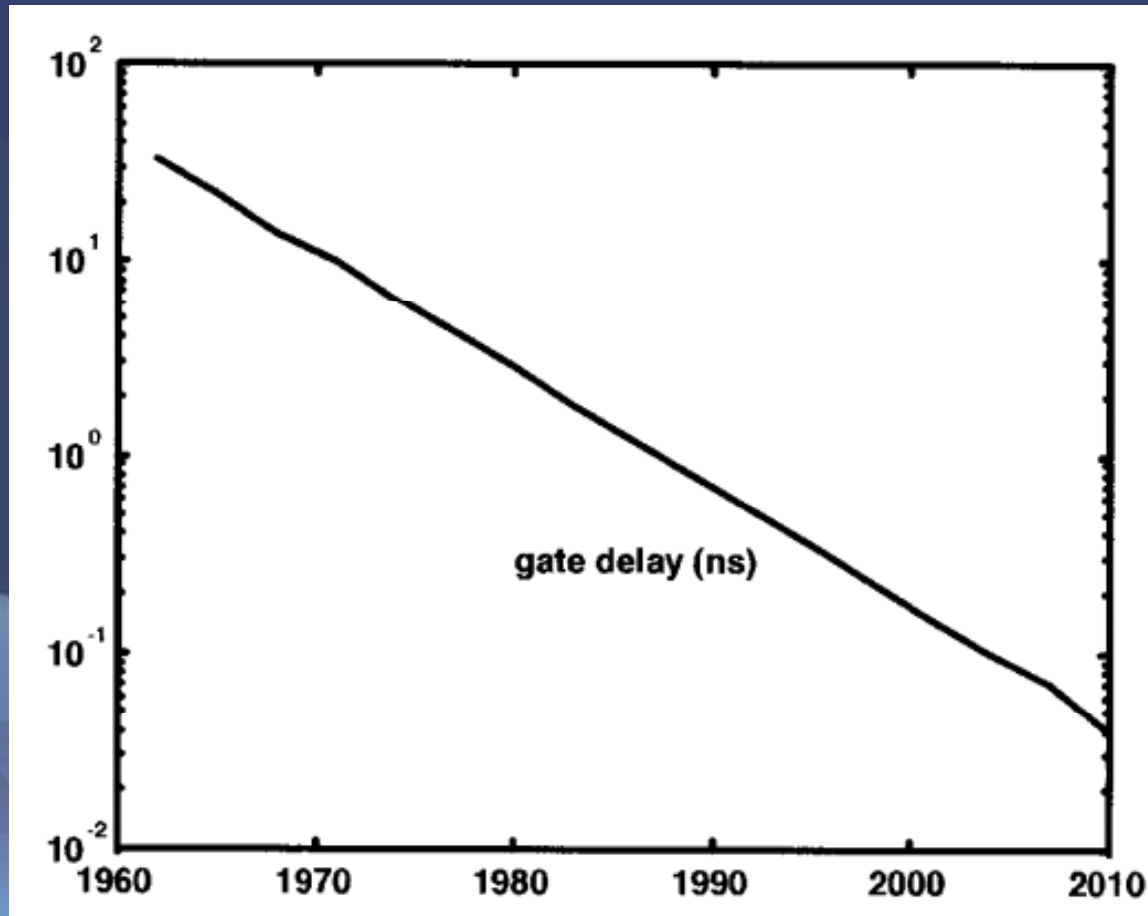
Minimum Feature Size

Technology Scaling



Number of components per chip

Technology Scaling



Propagation Delay

Technology Scaling Models

- Full Scaling (Constant Electrical Field)
 - ideal model, dimensions and voltage scale together by the same factor S
- Fixed Voltage Scaling
 - most common model until recently
 - only dimensions scale, voltages remain constant
- General Scaling
 - most realistic for today's situation
 - voltages and dimensions scale with different factors

Scaling Relationships for Long Channel Devices

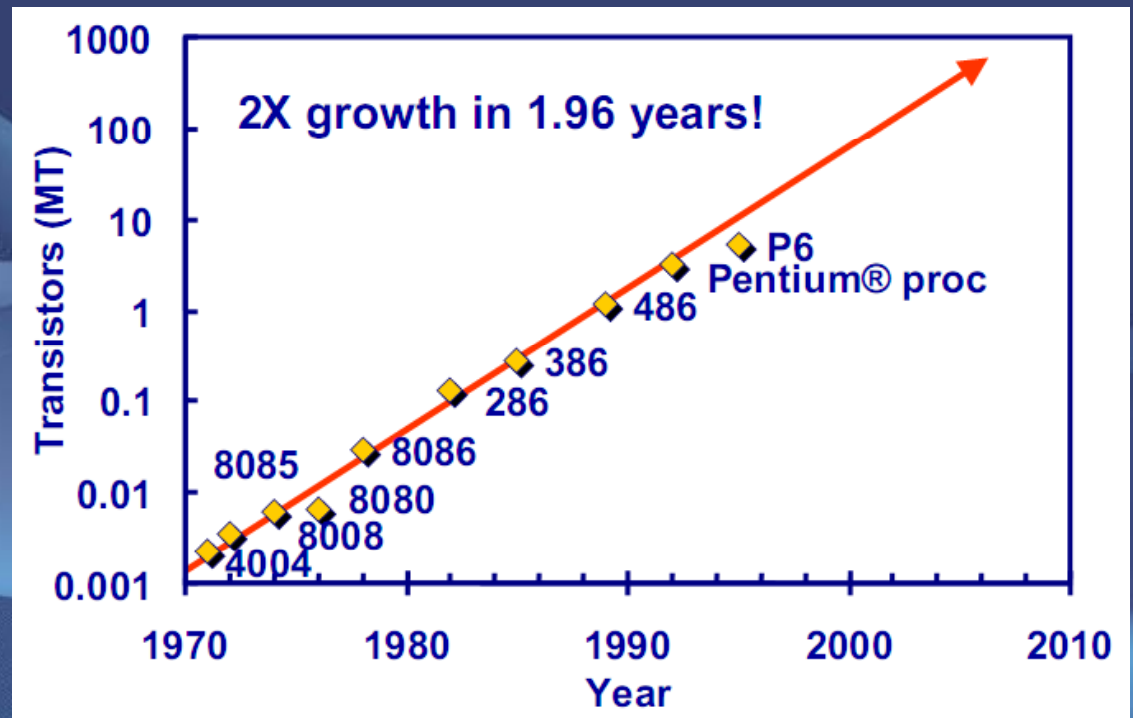
Parameter	Relation	Full Scaling	General Scaling	Fixed Voltage Scaling
W, L, t_{ox}		$1/S$	$1/S$	$1/S$
V_{DD}, V_T		$1/S$	$1/U$	1
N_{SUB}	V/W_{depl}^2	S	S^2/U	S^2
Area/Device	WL	$1/S^2$	$1/S^2$	$1/S^2$
C_{ox}	$1/t_{ox}$	S	S	S
C_L	$C_{ox}WL$	$1/S$	$1/S$	$1/S$
k_n, k_p	$C_{ox}W/L$	S	S	S
I_{av}	$k_{n,p} V^2$	$1/S$	S/U^2	S
t_p (intrinsic)	$C_L V / I_{av}$	$1/S$	U/S^2	$1/S^2$
P_{av}	$C_L V^2 / t_p$	$1/S^2$	S/U^3	S
PDP	$C_L V^2$	$1/S^3$	$1/SU^2$	$1/S$

Transistor Scaling for Velocity Saturated Devices

Parameter	Relation	Full Scaling	General Scaling	Fixed-Voltage Scaling
W, L, t_{ox}		$1/S$	$1/S$	$1/S$
V_{DD}, V_T		$1/S$	$1/U$	1
N_{SUB}	V/W_{depl}^2	S	S^2/U	S^2
Area/Device	WL	$1/S^2$	$1/S^2$	$1/S^2$
C_{ox}	$1/t_{ox}$	S	S	S
C_{gate}	$C_{ox}WL$	$1/S$	$1/S$	$1/S$
k_n, k_p	$C_{ox}W/L$	S	S	S
Current Density	$I_{sat}/Area$	S	S^2/U	S^2
R_{on}	V/I_{sat}	1	1	1
P	$I_{sat}V$	$1/S^2$	$1/U^2$	1

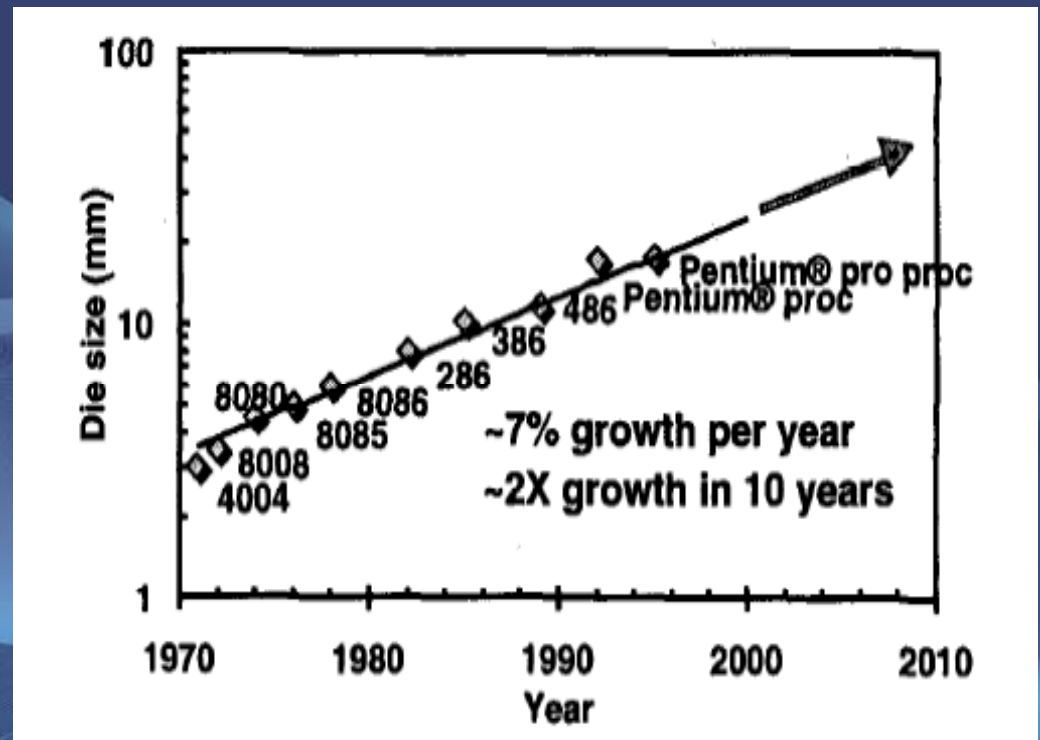
Microprocessor Scaling

- Processors used for comparison are 'Lead Microprocessors'.
- Indicates a doubled growth in transistor count every 2 years.



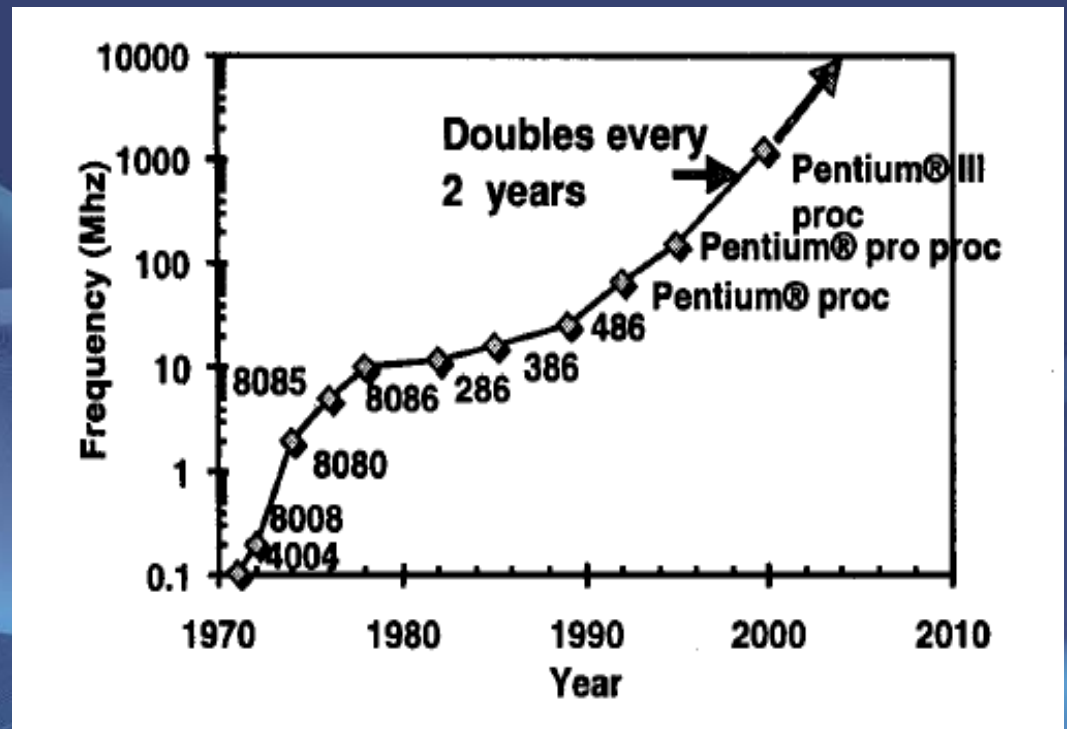
Die Size Trend

- Growth in die size with technology scaling.
- Graph indicates 7% growth per year and doubled growth in 10 years.



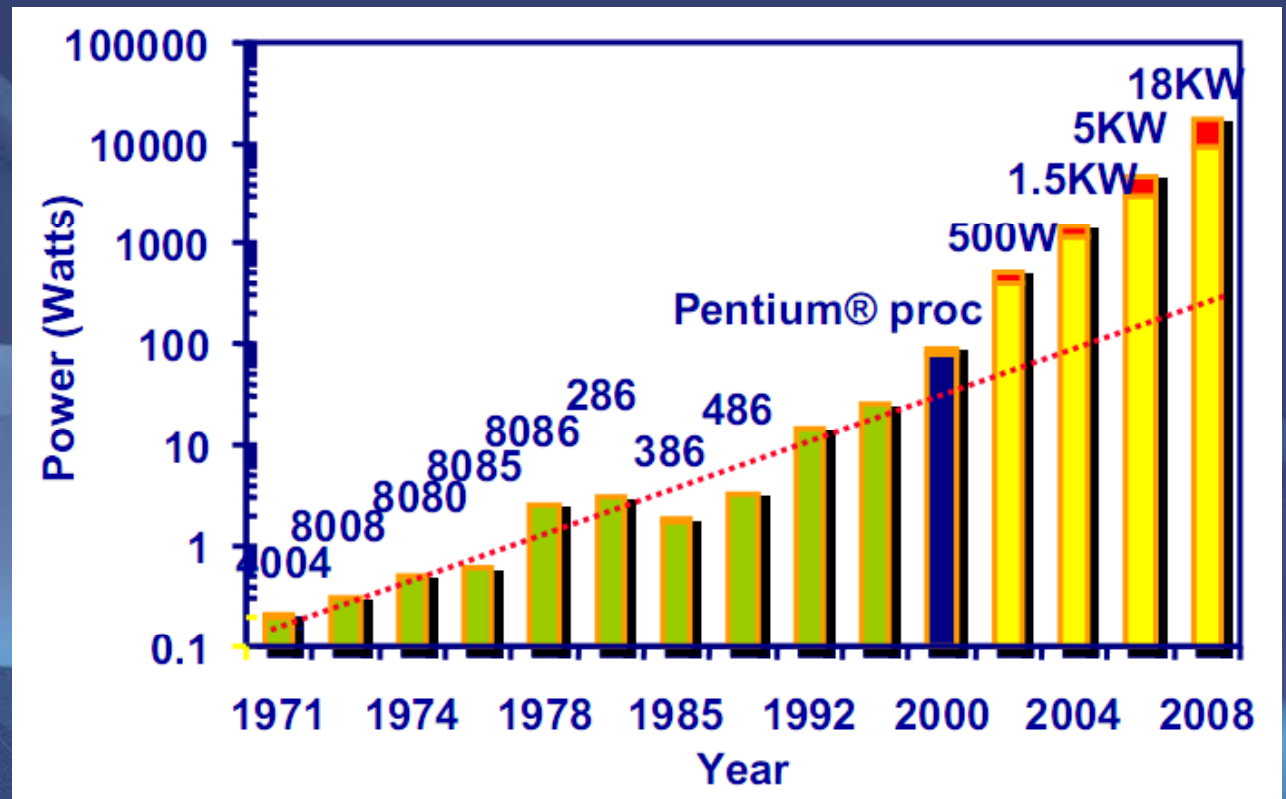
Operation Frequency Trend

- Initially increase in operating frequency was rapid.
- In the recent past operating frequency has been doubling every two years.

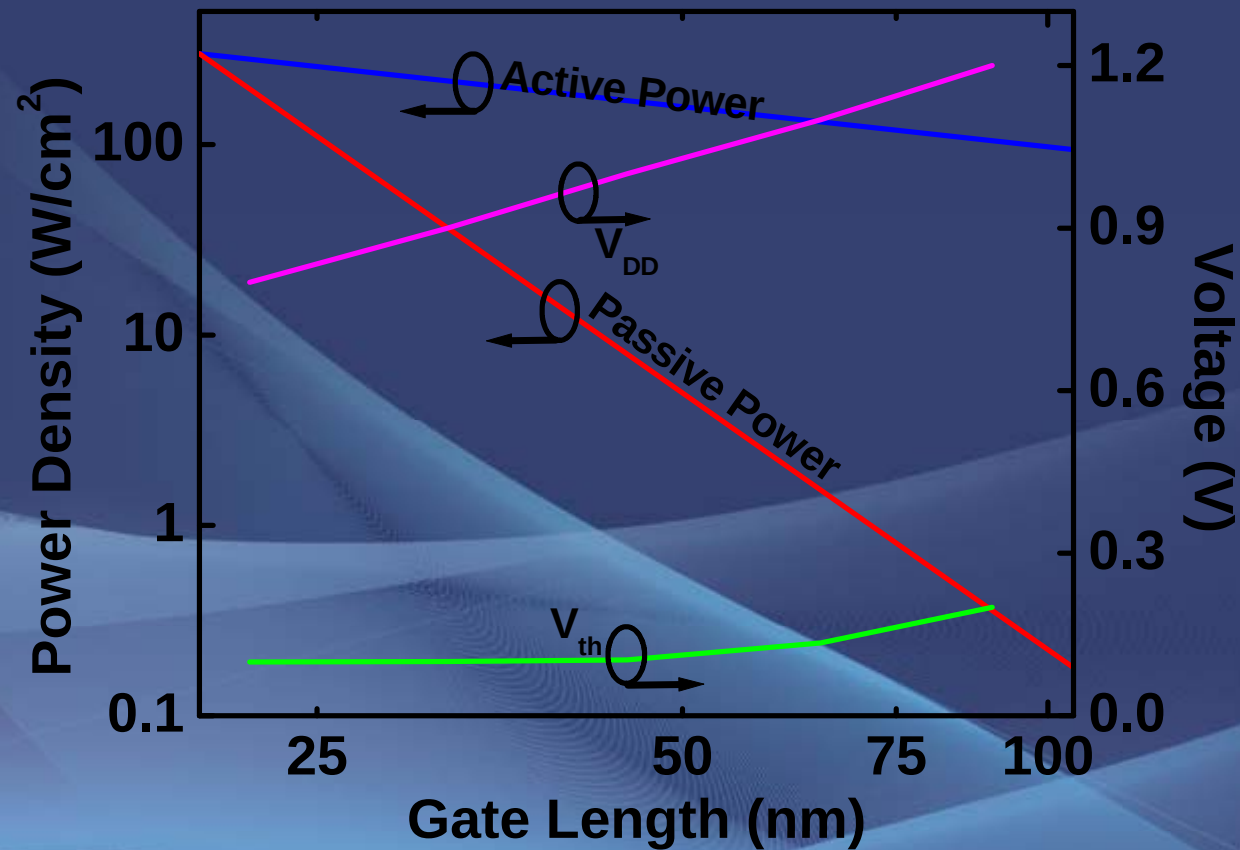


Microprocessor Power

- Continuous increase in power dissipation except for the one dip.
- Dip caused due to NMOS to CMOS transition.

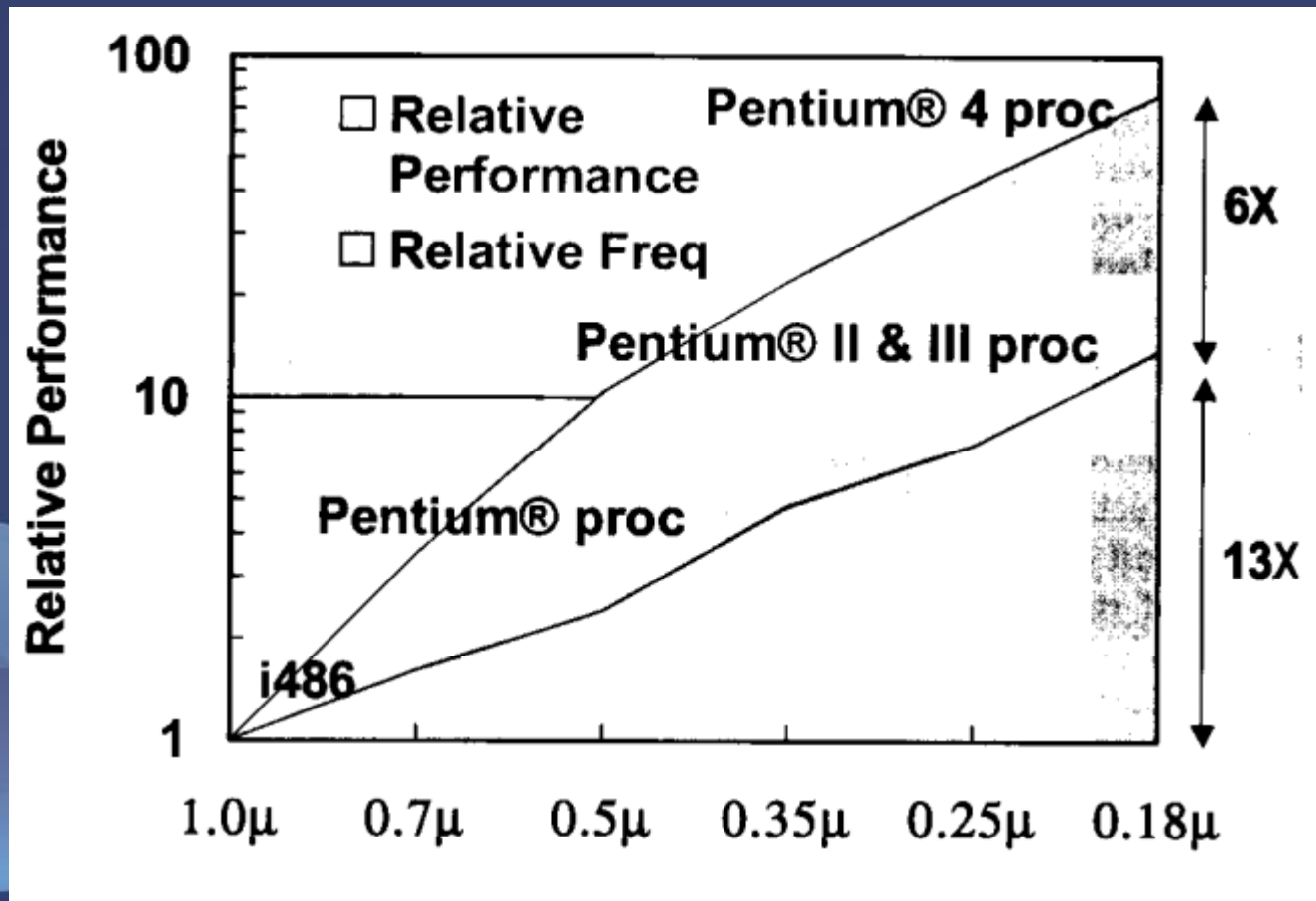


Gate Length Scaling Trends



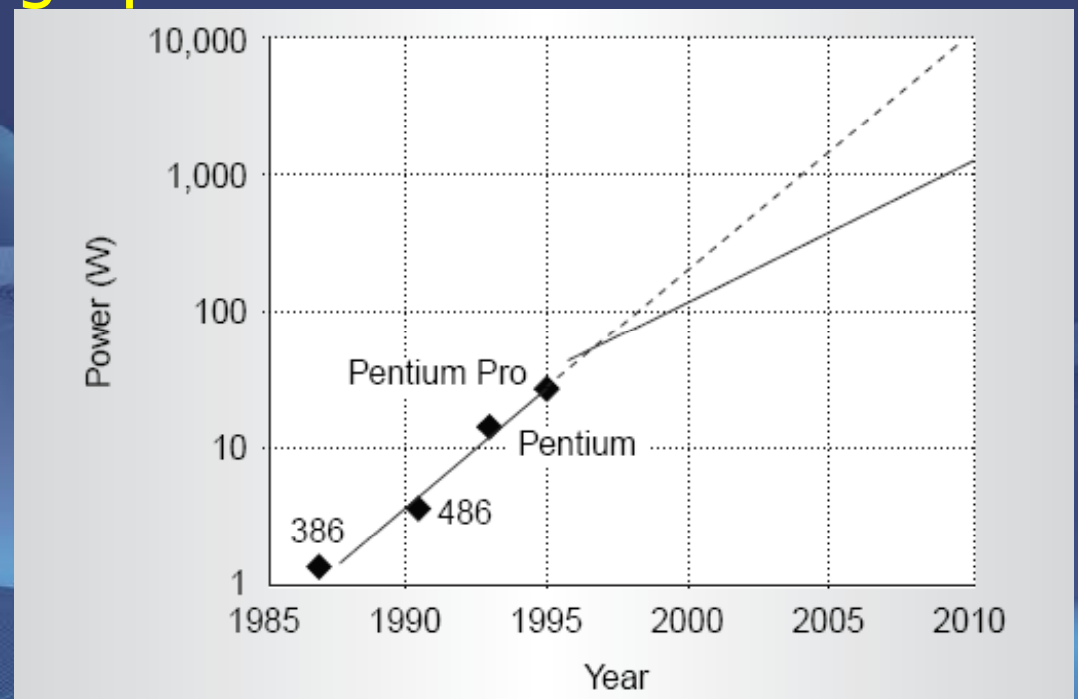
Puri *et. al.*, *Nano Lett.*, 2003

Microprocessor Performance



Power Dissipation Projection

- Considering only active power, power dissipation increases from 100W in 1999 to 2000W in 2010.
- Dotted line indicates the power dissipation including the leakage power.



Summary of trends

- Assuming technology scaling continues following the trend seen before, the following characteristics are observed every technology generation (i.e. every 2 years).
 - Electrical nodes in a given area doubles.
 - Die size grows by 14%.
 - Supply voltage decreases.
 - Frequency doubles.

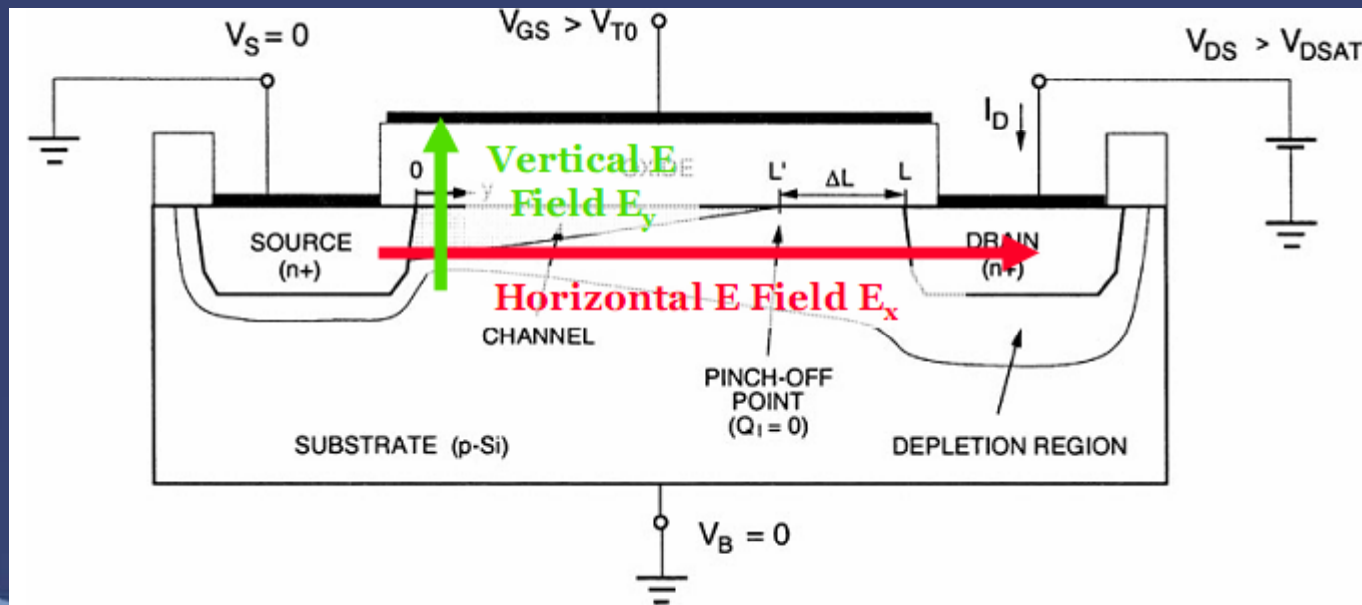
Problems Faced

- Threshold voltage to be scaled aggressively
- Reduced V_{th} results in higher leakage current
- Temperature on the die increases → higher resistance
- Interconnect delay becomes significant
- Soft error rate increases with scaling

Short Channel Effects

- Short-channel device: channel length is comparable to depth of drain and source junctions and depletion width
 - In general, visible when $L \sim 1\mu\text{m}$ and below
- Short-channel effects
 - Carrier velocity saturation
 - Mobility degradation
 - Threshold voltage variation
 - VT Roll-Off
 - Drain-Induced Barrier Lowering
 - Oxide breakdown
 - Avalanche breakdown

Velocity Saturation



Vertical Electric Field

1980	1995	2001
$E_y = 5V/1000\text{\AA} = 50 \times 10^4 \text{ V/cm}$	$E_y = 3.3V/75\text{\AA} = 4.4 \times 10^6 \text{ V/cm}$	$E_y = 1.2V/22\text{\AA} = 5.5 \times 10^6 \text{ V/cm}$

Horizontal Electric Field

1980	1995	2001
$E_x = 5V/5\mu\text{m} = 10^4 \text{ V/cm}$	$E_x = 3.3V/0.35\mu\text{m} = 9.4 \times 10^4 \text{ V/cm}$	$E_x = 1.2V/0.1\mu\text{m} = 1.2 \times 10^5 \text{ V/cm}$

Velocity Saturation

- As the horizontal E field grows, so does the velocity of the electrons
- As the gate shrinks, the velocity reaches the point where it cannot increase as much with increasing E field
- This is due to velocity saturation
 - Electrons become so energetic that they scatter (crash into the crystal lattice)

Alpha-Power MOSFET Model

T. Sakurai and A. R. Newton, "Alpha-power law MOSFET model and its application to CMOS inverter delay and other formulas," IEEE J. Solid-State Circuits, vol. 25, pp. 584–593, 1990.

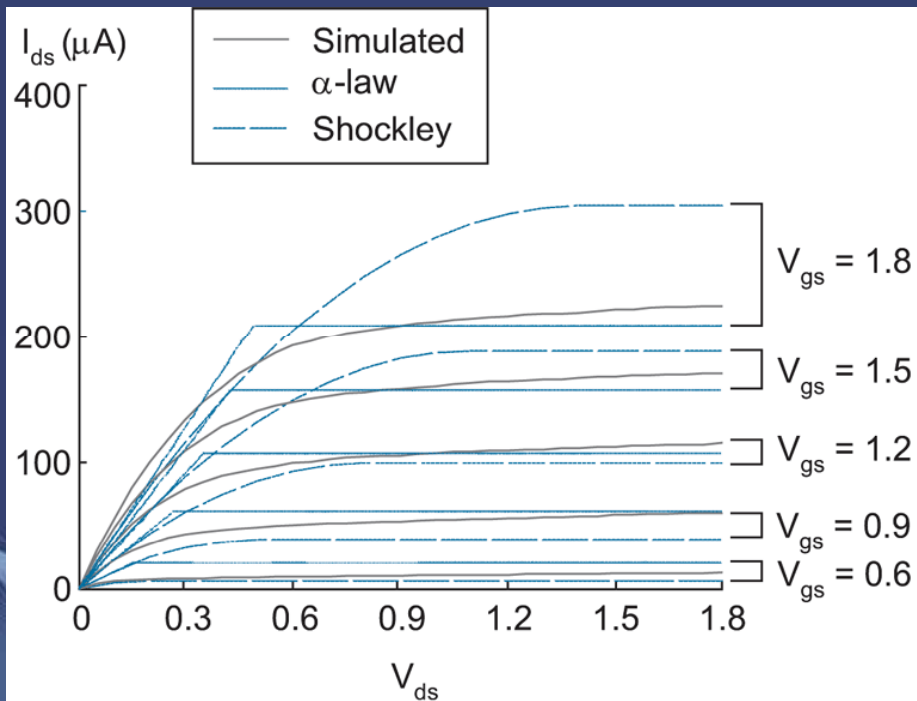


FIG 2.17 I-V characteristics for nMOS transistor with velocity saturation

At low lateral E-fields, V_{ds}/L , current increases linearly with E-field

At high fields, $E = E_{sat}$

Carrier velocity saturates due to carrier scattering = $v_{sat} (= \mu E_{sat})$

$$I_{ds} = \mu C_{ox} W/L (V_{gs} - V_t)^2$$

---no velocity saturation

$$I_{ds} = C_{ox} W (V_{gs} - V_t) v_{sat}$$

---complete velocity saturation

Practical situation: carrier velocity doesn't increase linearly with field but is not completely velocity saturated....

Sakurai Model: $I_{ds} \propto (V_{gs} - V_t)^\alpha$

$1 < \alpha < 2$, is the velocity saturation index, determined by curve fitting....also accounts for mobility degradation due to high vertical field (V_{gs}/t_{ox})

Mobility degradation

- MOS I/V equations depend on surface mobility μ_n (or μ_p)
 - Surface mobility is the mobility of the minority charge carriers at the surface of the channel
- In short-channel devices, μ_n and μ_p are not constant
 - As vertical electric field E_Y increases, surface mobility decreases because the electrons' wave function extends increasingly into the extremely low-mobility oxide
 - μ_0 = low-field mobility, η is empirical constant
 - As V_{GS} increases, effective surface mobility decreases

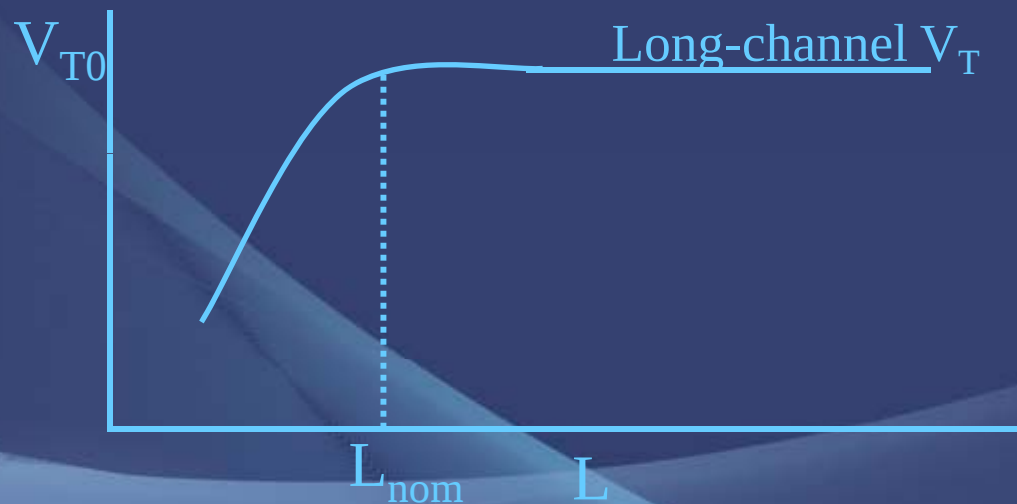
$$\mu_{eff} = \frac{\mu_0}{1 + \eta(V_{GS} - V_T)}$$

Threshold voltage dependence on L

- Until now, threshold voltage assumed constant
 - V_T changed only by substrate bias V_{SB}
- In threshold voltage equations, channel depletion region assumed to be created by gate voltage only
- Depletion regions around source and drain neglected: valid if channel length is much larger than depletion region depths
- In short-channel devices, depletion regions from drain and source extend into channel

Threshold voltage roll-off...

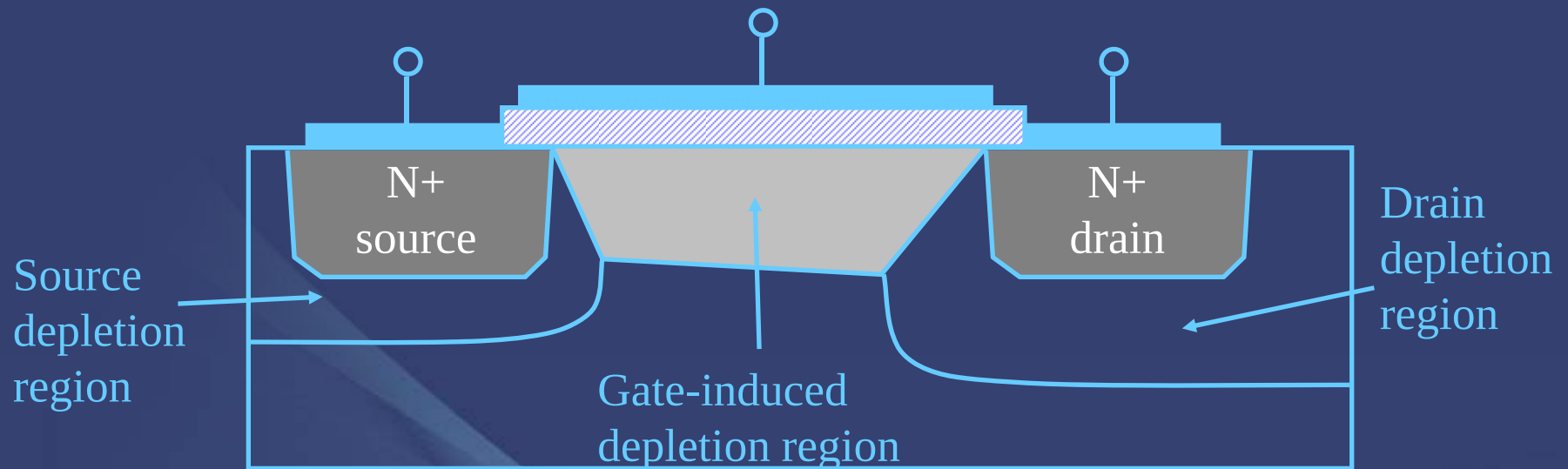
Graphically: V_{T0} versus channel length L



V_T Roll-off:

V_T decreases rapidly with channel length

Reason for V_t Roll-Off....



- Even with $V_{GS}=0$, part of channel is already depleted
- Bulk depletion charge is smaller in short-channel device $\rightarrow V_t$ is smaller

Threshold voltage roll-off....

- Change in V_{t0} :
 - x_{dS} , x_{dD} : depth of depletion regions at S, D
 - x_j : junction depth

$$\Delta V_{t0} = \frac{1}{C_{ox}} \sqrt{2q\epsilon_{Si} N_A |2\phi_F|} \cdot \frac{x_j}{2L} \left[\left(\sqrt{1 + \frac{2x_{dS}}{x_j}} - 1 \right) + \left(\sqrt{1 + \frac{2x_{dD}}{x_j}} - 1 \right) \right]$$

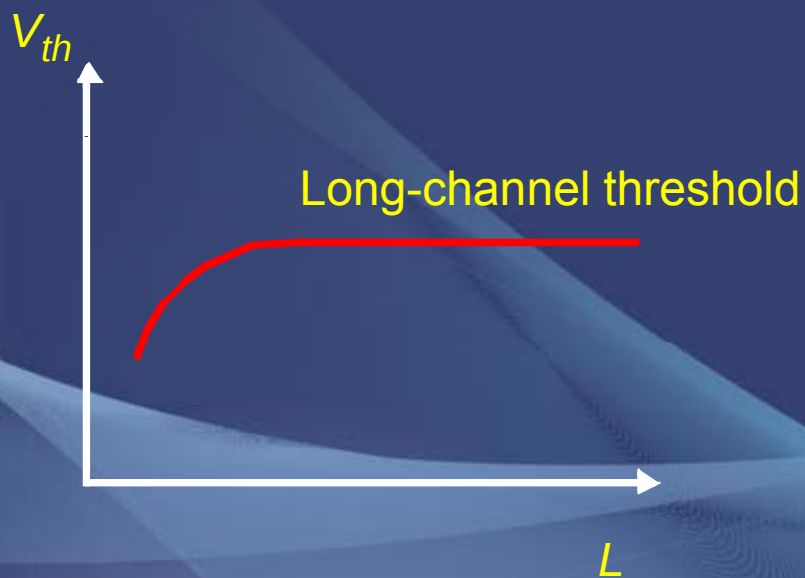
- ΔV_{t0} is proportional to (x_j/L)
 - For short channel lengths, ΔV_{t0} is large
 - For large channel lengths, term approaches 0

DIBL

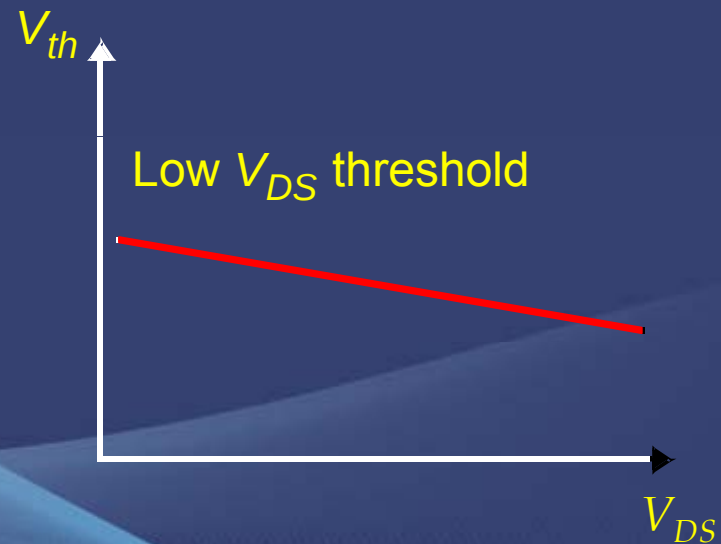
- Drain-induced barrier lowering (DIBL)
 - Drain voltage V_{DS} causes change in threshold voltage
 - As V_{DS} is increased, threshold voltage decreases
- Cause: depletion region around drain
 - Depletion region depth around drain depends on drain voltage
 - As V_{DS} is increased, drain depletion region gets deeper and extends further into channel
 - For very large V_{DS} , source and drain depletion regions can meet → *punch-through!*
- Issue: results in uncertainty in circuit design

Effect of SCE and DIBL on V_{th}

- $V_{th} = V_{th_long-channel} - \text{SCE} - \text{DIBL}$



Threshold as a function of the length (for low V_{DS})



Drain-induced barrier lowering (DIBL) (for low L)

Threshold voltage variation

Short-channel effects cause threshold voltage variation:

- V_t rolloff
 - As channel length L decreases, threshold voltage decreases
- Drain-induced barrier lowering
 - As drain voltage V_{DS} increases, threshold voltage decreases
- Hot-carrier effect
 - Threshold voltages drift over time
- Negative-Bias Temperature Instability (NBTI)
 - Issue in PMOS transistors
 - V_t drifts over time
 - Typical stress temperature 100-150 C
 - Typical oxide electric fields of 5-6 MV/cm

Threshold voltage variation

- Hot-carrier effect
 - increased electric fields causes increased electron velocity
 - high-energy electrons can tunnel into gate oxide
 - This changes the threshold voltage (increases V_t for NMOS)
 - Can lead to long-term reliability problems

Threshold voltage variation

- Hot electrons
 - High-velocity electrons can also impact the drain, dislodging holes
 - Holes are swept towards negatively-charged substrate → cause substrate current
 - Called *impact ionization*
 - This is another factor which limits the process scaling → voltage must scale down as length scales

Threshold voltage variations

- Summary of threshold variations in short-channel devices
 - V_t rolloff: threshold voltage reduces as channel length L reduces
 - DIBL: threshold voltage reduces as V_{DS} increases
 - Hot-carrier effect: threshold voltage drifts over time as electrons tunnel into oxide
 - NBTI—causes V_t increase in PMOS transistors, strong dependence on Temperature.

Subthreshold Leakage

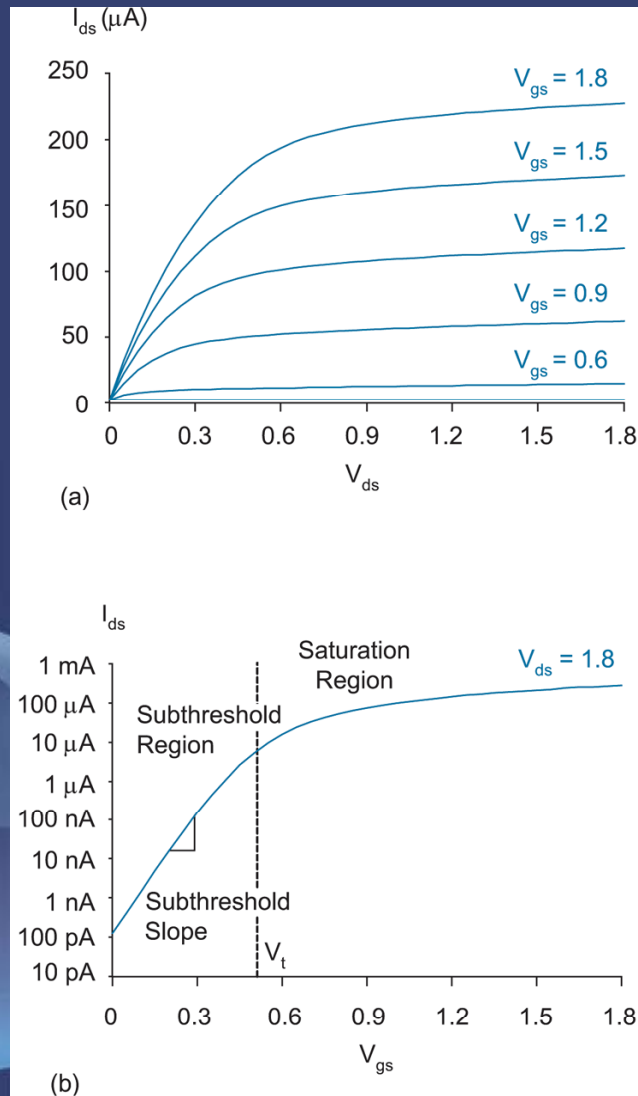


FIG 2.15 Simulated I-V characteristics

- *Dominant leakage mechanism*
- *Increases exponentially with temperature and V_t*

$$S = \left(\frac{d(\log I_d)}{dV_g} \right)^{-1} = \left(\frac{\partial V_g}{\partial \psi_s} \right) \left(\frac{\partial \psi_s}{\partial (\log I_d)} \right) = \left(1 + \frac{C_{dm}}{C_{ox}} \right) \frac{kT}{q} \ln(10)$$

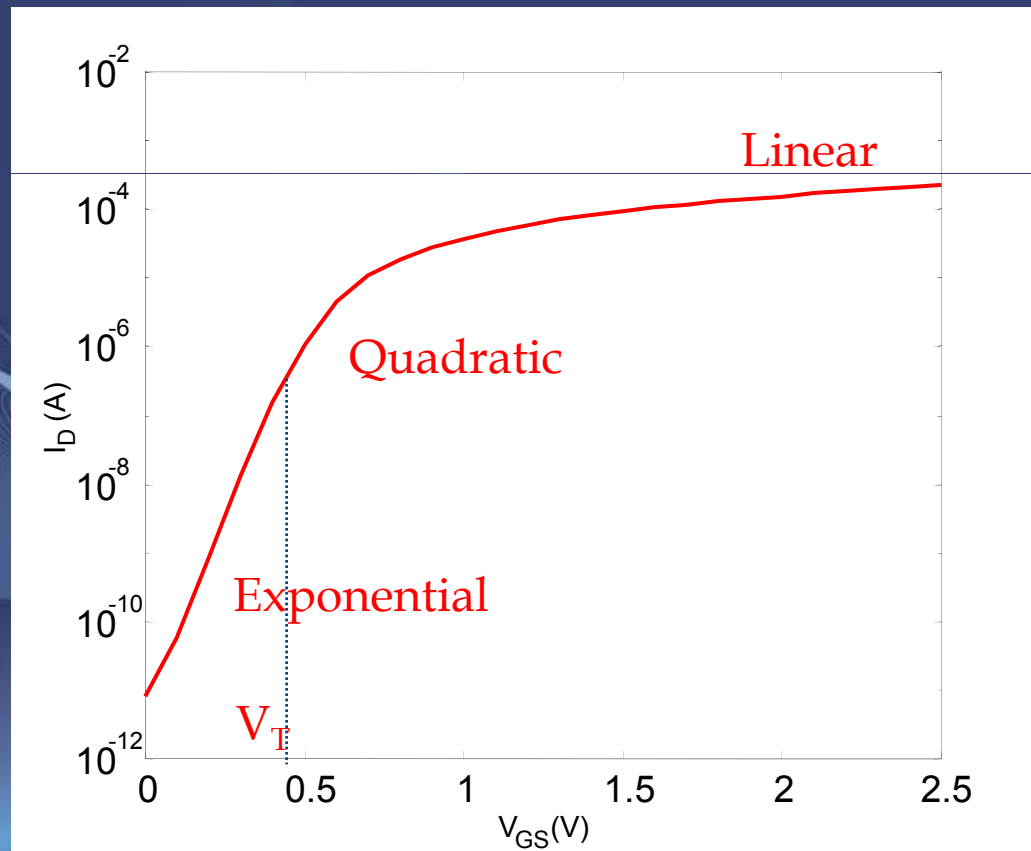
Sub-threshold conduction (1)

- When $V_{GS} < V_T$, transistor is “off”
 - However, small drain current I_D still flows
 - Called *subthreshold leakage* current
- Model for subthreshold current:

$$I_D(\text{subthreshold}) = I_S W e^{\frac{q}{kT}(AV_{GS} + BV_{DS})}$$

- Increases as V_{GS} increases (potential barrier lowered)
- Increases as V_{DS} increases (DIBL)

Sub-Threshold Conduction (2)



The Slope Factor

$$I_D \sim I_0 e^{\frac{qV_{GS}}{nkT}}, \quad n = 1 + \frac{C_D}{C_{ox}}$$

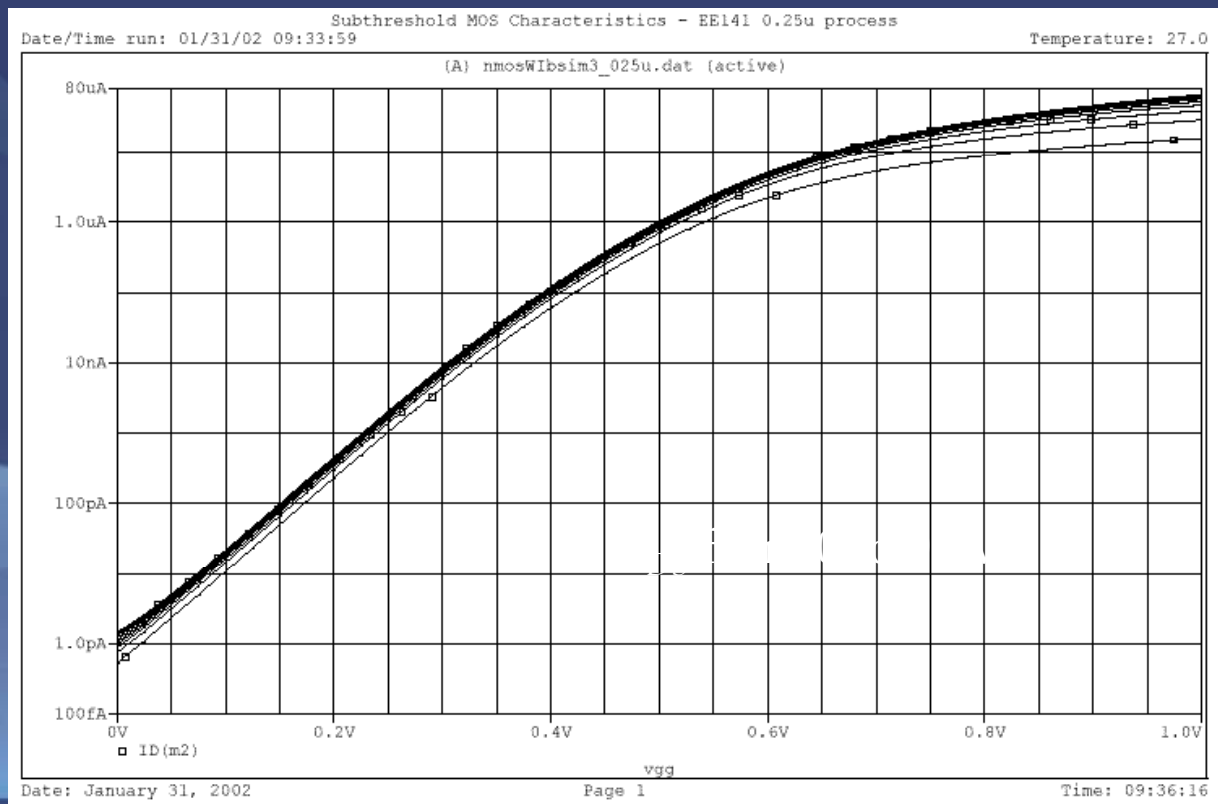
S is ΔV_{GS} for $I_{D2}/I_{D1} = 10$

$$S = n \left(\frac{kT}{q} \right) \ln(10)$$

Typical values for S :
60 .. 100 mV/decade

Sub-Threshold I_D vs V_{GS}

$$I_D = I_0 e^{\frac{qV_{GS}}{nkT}} \left(1 - e^{-\frac{qV_{DS}}{kT}} \right)$$



Sub-Threshold I_D vs V_{DS}

$$I_D = I_0 e^{\frac{qV_{GS}}{nkT}} \left(1 - e^{-\frac{qV_{DS}}{kT}} \right) (1 + \lambda \cdot V_{DS})$$

